

Notice of References Cited

Application/Control No.

10/522,533

Applicant(s)/Patent Under

Reexamination

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Examiner

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Art Unit

1792

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U.S. PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A US-6,579,833	06-2003	McNallan et al.	508/100
B	US-			
C	US-			
D	US-			
E	US-			
F	US-			
G	US-			
H	US-			
I	US-			
J	US-			
K	US-			
L	US-			
M	US-			

FOREIGN PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
N					
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NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
U	Matsui et al, Three-dimensional nanostructure fabrication by focused-ion-beam chemical vapor deposition, J. Vac. Sci. Technol. B 18(6), Nov/Dec 2000, p. 3181-3184.
V	Kusunoki et al, Aligned carbon nanotube film self-organized on a SiC wafer, Jpn. J. Appl. Phys. Vol. 37 (1998), p. L605-L606.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))
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